



Editors:

Filipe Vaz
Portugal

Nicolas Martin
France

Martin Fenker
Germany

eISBN: 978-1-60805-156-4



Metallic Oxynitride Thin Films by Reactive Sputtering and Related Deposition Methods: Processes, Properties and Applications

www.benthamscience.com/ebooks/9781608051564

About the ebook

This e-book provides valuable information about the process modeling, fabrication and characterization of metallic oxynitride-based thin films produced by reactive sputtering and some related deposition processes

Contents

- ▶ Modelling of Reactive Sputter Deposition of Oxynitrides
- ▶ Reactive Gas Pulsing Process for Oxynitride Thin Films
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- ▶ Properties of Oxynitride Thin Films for Biomedical Applications

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